**Diamond CVD Plus Graphene System**

- Water cooled stainless steel high vacuum chamber
- Easy filament holder flange
- DC low voltage power supply
- Four Mass Flow Controllers of various ranges
- Standard pressure gauges
- Mechanical and Optional Turbo vacuum pump
- Optional stainless steel load lock chamber
- Linear motion motorized control of Filament to substrate distance
- Versatile 2” diameter substrate heater with optional rotation.